EIGEMBox

Patented Plug-n-Play SECS/GEM Solution for Legacy Semiconductor Equipment

Enable SECS/GEM capability on your EXISTING equipment — instantly, safely, and cost-effectively.

Key Highlights

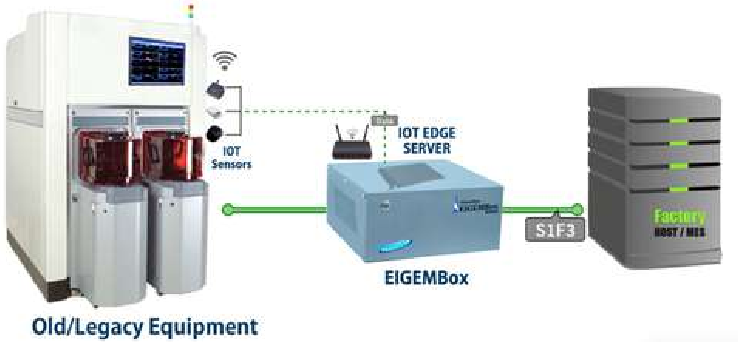
- ✓ Add or enhance SEMI E30 compliant SECS/GEM or E84 capability on any equipment
- ✓ Truly Plug-n-Play : No hardware or software installation on existing equipment required
- ✓ Successfully implemented on 80+ semiconductor equipment worldwide
- ✓ Saves huge cost in equipment upgrade and extends life of equipment
- ✓ Patented Technology in multiple countries
- ✓ Nothing needed from OEM, no license, no upgrade, nothing
- ✓ No side effects to the equipment of any kind

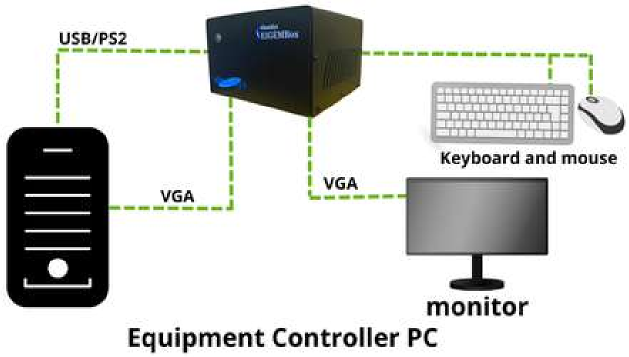
Core Capabilities

- Real-time data collection at 1-second frequency
- Remote recipe download, start, stop, and monitoring
- Remote desktop view of equipment screen
- Data capture: wafer maps, histograms, charts
- Integration with MES and factory systems
- External sensor and PLC connectivity
- RPA tools for preventive maintenance automation
- Full recipe management functions

Business Benefits

- Avoid expensive equipment replacement or OEM upgrades
- Extend usable life of legacy tools
- Accelerate smart factory and Industry 4.0 initiatives
- Future-proof automation with minimal risk
- Ideal for fabs, OSATs, R&D labs, and legacy lines





How It Works

- Connect VGA / DVI / HDMI from equipment display
- Connect USB (Keyboard/Mouse) if required
- EIGEMBox captures and interprets on-screen data
- Converts data into SECS/GEM / OPC / Modbus
- Enables host communication & automation instantly

Core Benefits

- Enables SECS/GEM, OPC, or Modbus on existing equipment
- No software installation on the tool
- No PLC or controller modification required
- Works with legacy & non-standard equipment
- Supports Industry 4.0 & Smart Factory initiatives

Automation Capabilities Enabled

- Real-time Data Collection & Analysis
- Fault Detection & Classification (FDC)
- Recipe Download & Management
- Remote Start / Stop
- OEE, Yield & Cycle Time Improvement
- Reduced manufacturing cost and manual dependency

Advanced Features

Pattern Recognition & Pattern Matching

- Screen capture & extraction: Wafer maps, Histograms, Charts & graphs
- RPA Tool – Automate repetitive tasks (including PM activities)
- Data collection from external sensors or PLCs
- Remote Desktop access to equipment PC (without networking)

AMHS & Fab Integration

- Supports E84 & E87 integration
- Successfully deployed in 200mm fabs
- Enables AMHS without modifying equipment controllers

Proven Use Cases

- Enhancing SECS/GEM communication with full parameter exchange
- Reducing latency and improving host interaction
- Extracting non-standard data beyond traditional SECS/GEM limitations
- Rapid enablement of automation on aging tools

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OUR LOCATION

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eInnoSys

Fab/Assembly Automation | AI & Machine Learning | Equipment Software | Industry 4.0